

L Number	Hits	Search Text	DB	Time stamp
1	67	(ghoshal cordes dimilia doyle speidell).in. and thermoelectric	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:31
8	285	438/20.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:31
15	215	438/20.ccls. and (metal or copper or cu)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:34
22	69	438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:37
29	101	438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:35
36	144	(438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:36
43	106	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and @ad<20001130	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:37
50	106	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:38
57	56	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:37
64	128	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and @ad<20001207 (((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:37
71	137	438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:38
78	115	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:38
85	84	((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3)) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:03

92	47	(((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:38
99	104	(((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:42
106	99	(((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 11:43
113	72	(((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:00
120	1286	(((((438/20.ccls. and ((metal or copper or cu) near15 (mask resist photoresist pattern\$3))) (438/20.ccls. and ((conductive conducting) near15 (mask resist photoresist pattern\$3)))) and (438/20.ccls. and ((metal or copper or Cu or conducting or conductive) near15 etch\$3))) and @rlad<20001207)) and (point tip) near15 (metal copper Cu conductive conducting) (point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:45
127	232	(((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:48
134	201	(((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:48
141	55	(((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:03
148	212	(((((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) (((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:37
155	0	(((((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) (((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207)) and (peltier thermoelectric thermo-electric cooler)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 16:44

162	0	((((((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip needle) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207)) and (seeb?ck)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:38
169	1490	(point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:47
176	266	(((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:48
183	223	(((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:28
190	59	(((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 14:48
197	234	((((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 16:44
204	876	(peltier thermoelectric thermo-electric) and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper Al aluminum))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 16:48
211	652	(peltier thermoelectric thermo-electric) and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:26
218	329	(peltier ((thermoelectric thermo-electric) adj cool\$3)) and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 16:56
225	171	((peltier thermoelectric thermo-electric) adj2 cool\$3) and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:19
232	27	((peltier thermoelectric thermo-electric) adj2 cool\$3).ti.ab. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:25
239	12123	136/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:25
246	347	136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:09

253	346	((136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:27
260	306	((136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207))) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:16
267	70	((136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207))) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:28
274	314	((136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207))) and @ad<20001207) (((136/\$.ccls. and ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper))) not ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @ad<20001207) ((((point tip tipped needle cone pointed conical conically conicly pyramid pyramidal pyramidally sharp) near12 ((metal copper Cu conductive conducting) near3 etch\$3)) same (resist photoresist)) and @rlad<20001207))) and @rlad<20001207)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:43
281	629	136/203,205.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:46
288	23	136/203,205.ccls. and etch\$3 and (resist photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 17:46

302	2047	etch\$3 near12 ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:15
309	235	(etch\$3 near12 ((point pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:16
316	775	etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:15
323	81	(etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:16
330	68	((etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)) and @ad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:16
337	11	((etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)) and @rlad<20001207	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:16
344	68	((etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)) and @ad<20001207) (((etch\$3 near12 ((pointed projection tip pointy needle tipped cone conical conically conicly pyramid pyramidal pyramidally sharp) near5 (metal Cu copper aluminum))) near15 (resist photoresist)) and @rlad<20001207)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/06/19 18:16